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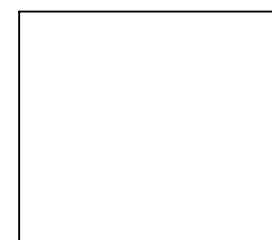
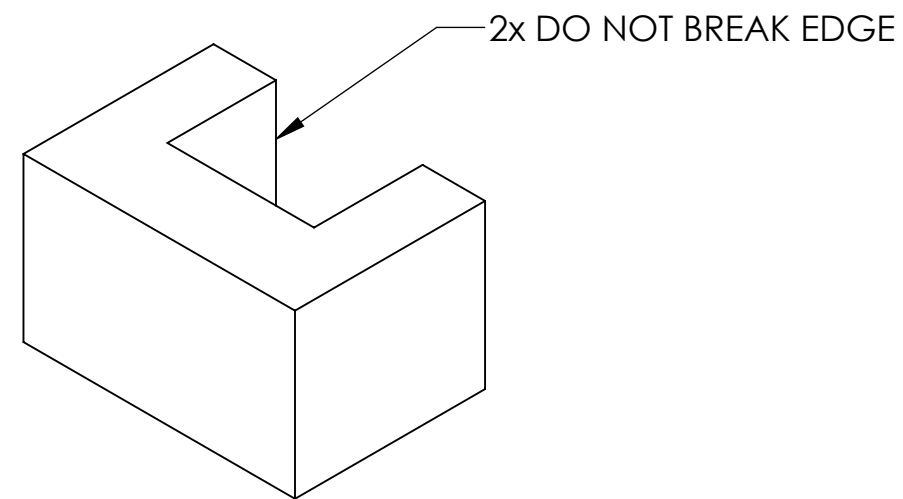
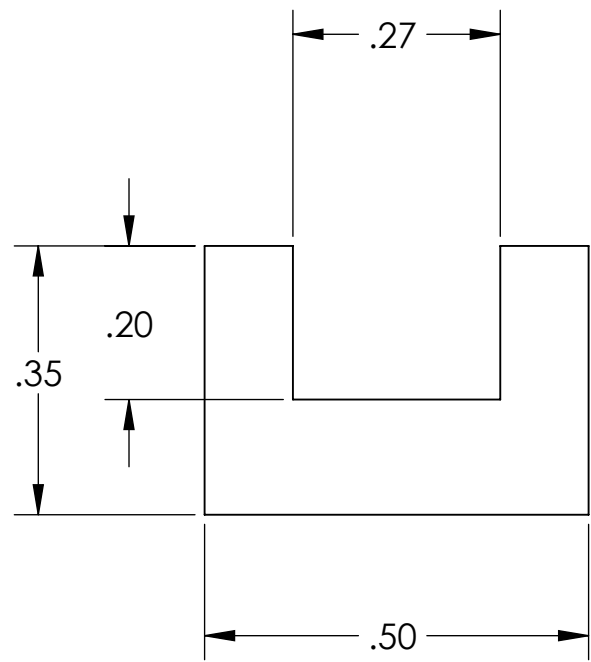
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NOTES CONTINUED:

- 5. BAG AND TAG WITH PART AND SERIAL NUMBER
- 6. MACHINE ALL SURFACES TO REMOVE OXIDES AND MILL FINISH, USE OF ABRASIVE REMOVAL TECHNIQUES IS NOT ALLOWED.
- 7. ALL PARTS SHALL BE MANUFACTURED IN ACCORDANCE WITH LIGO SPECIFICATION E0900364.

REV.	DATE	DCN #	DRAWING TREE #
v1	19 APR 2013	E1300287-x0	-
-	-	-	-
-	-	-	-



D1300355 CALIGO OMC DIODE MOUNT SHIM ALIGNMENT BLOCK, PART PDM REV: X-000, DRAWING PDM REV: X-000

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C

B

A

D

C

B

A

NOTES AND TOLERANCES: (UNLESS OTHERWISE SPECIFIED)

DIMENSIONS ARE IN		1. INTERPRET DRAWING PER ASME Y14.5-1994.	
TOLERANCES:		2. REMOVE ALL SHARP EDGES .005-.015, EXCEPT WHERE NOTED	
.XX ± .01		3. DO NOT SCALE FROM DRAWING.	
.XXX ± .005		4. ALL MACHINING FLUIDS MUST BE FULLY SYNTHETIC, FULLY WATER SOLUBLE AND FREE OF SULFUR, SILICONE, AND CHLORINE.	
ANGULAR ± 1°		MATERIAL	FINISH
		AISI 304	63 μinch

 SYSTEM ADVANCED LIGO NEXT ASSY	CALIFORNIA INSTITUTE OF TECHNOLOGY MASSACHUSETTS INSTITUTE OF TECHNOLOGY	SUB-SYSTEM ISC	PART NAME	
			αLIGO OMC DIODE MOUNT SHIM ALIGNMENT BLOCK	
DESIGNER	J.LEWIS	19 APR 2013	SIZE	DWG. NO.
DRAFTER	J.LEWIS	19 APR 2013	B	D1300355
CHECKER			SCALE: 4:1	PROJECTION:
APPROVAL				SHEET 1 OF 1

DESIGNER	J.LEWIS	19 APR 2013	SIZE	DWG. NO.	REV.
DRAFTER	J.LEWIS	19 APR 2013	B	D1300355	v1
CHECKER			SCALE: 4:1	PROJECTION:	
APPROVAL					SHEET 1 OF 1

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